

15986 U.S. PTO  
10/015276  
12/11/01

PATENT NUMBER and  
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10015276	FILING DATE 12/11/2001	CLASS 438	SUBCLASS 14	GAU 2842	EXAMINER PERT
<b>**APPLICANTS:</b> Hosoya Naoki; Takagi Yuuji; Shibuya Hisae; Obara Kenji;					
<b>**CONTINUING DATA VERIFIED:</b>					
<b>** FOREIGN APPLICATIONS VERIFIED:</b>					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/> RESCIND <input type="checkbox"/>					
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials				ATTORNEY DOCKET NO 16869P-036200US	
TITLE : Method and apparatus for inspecting defects in a semiconductor wafer					

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

<b>NOTICE OF ALLOWANCE MAILED</b>		<b>CLAIMS ALLOWED</b>	
		Total Claims	Print Claim for O.G.
<b>ISSUE FEE</b>		<b>DRAWING</b>	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg. Print Fig.
<input type="checkbox"/> <b>TERMINAL DISCLAIMER</b>		Primary Examiner PREPARED FOR ISSUE Application Examiner	
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